

same logical word¹, therefore producing a failure.

- Accumulation failures caused by two independent events, producing two or more errors on the same word. This second type of failures is independent of the ID, and has been previously studied in [5],[11].

Let us assume that the interleaving scheme shown in Figure 1 is used and that, as explained before, MCUs that exceed the interleaving distance always cause a failure. Let us define $e(n)$ as the probability that a given error event spans n columns and e^{ID} as the probability that an error event causes a direct failure when the interleaving distance is ID. Then, for a given ID value, the probability that an error event causes a direct failure is given by how likely MCUs span more than ID:

$$e^{ID} = \sum_{n=ID+1}^{\infty} e(n). \quad (1)$$

This basically adds the probabilities of all MCUs spanning more than ID columns.

Let us also define $p(n)$ as the probability that an event causes n cell errors (therefore being $p(1)$ the probability that a given event is an SEU, and $p(n)$, for $n>1$, the probability of an n -bit MCU). If we denote by α the average number of errors per event, then α can be computed as follows:

$$\alpha = \sum_{n=1}^{\infty} n \cdot p(n). \quad (2)$$

Under these assumptions, the probability of failure due to the two mentioned mechanisms can be studied: direct failure when an event provokes errors that exceed the ID, and accumulation failure caused by two independent events causing errors on the same word.

To study the memory reliability, the Mean Time to Failure (MTTF) will be used as a figure of merit. For direct failures, the MTTF is given by

$$MTTF|_d = \frac{1}{\lambda \cdot M \cdot e^{ID}}. \quad (3)$$

where λ is the per-word error event arrival rate and M is the memory size in words. This is a direct conclusion if we consider that events arrive following a Poisson distribution, since $MTTF = METF / \lambda$, and $METF = 1 / e^{ID}$ (being METF the Mean number of Events to Failure) [12].

For accumulation failures, the MTTF can be approximated when M is large by:

$$MTTF|_a \cong \frac{1}{\lambda \cdot \alpha} \cdot \sqrt{\frac{\pi}{2 \cdot M}}. \quad (4)$$

The proof of this can be found in [5], where the scenario in which MCUs accumulate in memories is modeled.

The total MTTF of the memory will be determined by both effects. This is equivalent to the traditional model of two elements connected in series such that the system fails when one of them fails [13]. For those systems, when the probability of failure is uniformly distributed with time, the total MTTF can be expressed as a function of the partial MTTFs as,

$$MTTF = \frac{1}{\frac{1}{MTTF_1} + \frac{1}{MTTF_2}}. \quad (5)$$

In the memory case, the direct failures have a uniformly distributed probability of failure with time (all the direct failures have the same probability of occurrence), but the accumulation failures do not. This is due to the fact that as errors accumulate, a new error is more likely to affect a word that already contains a previous error causing a failure (see for example [14] for more details). Therefore, in our case, equation (5) is only an approximation for the MTTF of the memory:

$$MTTF_{memory} \cong \frac{1}{\frac{1}{MTTF_d} + \frac{1}{MTTF_a}}. \quad (6)$$

This approximation will be used in the following section to assess the impact of the ID selection on the MTTF. Note that the ID affects the probability of direct failure, e^{ID} , per expression (1), and this probability is related to the MTTF per expressions (3) and (6).

III. SELECTION OF THE INTERLEAVING DISTANCE

In this section, and based on the previous analysis, the selection process of the ID is presented now using a real case study. Four different memory technologies have been studied which have been previously characterized with real radiation experiments. They correspond to advanced geometries (65nm and 45nm) for which MCUs are a major concern and large IDs are normally used to ensure that no direct failures occur. The memories were exposed to white beams up to 800 MeV at the LANCE site and neutron beams up to 180 MeV at the TSL site. Multiple devices were used and for each one multiple tests were performed. For all tests, the mean time between upsets was much larger than the mean time of an SRAM read cycle for the entire memory. Such configuration was achieved by adjustment of the flux intensity. Once an error was detected, a checking procedure was launched to check the error types. More details on the experiments are given on [11].

The purpose of the characterization process has been to determine the two parameters described in the previous section: $e(n)$ (probability that an MCU spans n columns) and $p(n)$ (probability of an n -error event).

Once these parameters have been determined, the value of α (average number of errors per event) has been calculated through (2) using $p(n)$. The results for the different memories are shown in Table I. The values for the two types of 65nm memories were added together so that a single value is shown. However, the individual α would be similar in any case.

On the other hand, the values of $e(n)$ for the four types of memories were used to compute the probability of an event causing a direct failure for each ID value (e^{ID}), using (1). The results are shown in Figure 2, where it can be observed that these values decrease as the ID increases. This is obvious, as the probability of a direct failure lowers with higher values of IDs. But, those high IDs, although safer, introduce an

¹ Not all the MCUs exceeding the ID will cause a failure, because the MCU pattern (physical distribution) also affects. In this paper, this effect will be disregarded, and therefore all such MCUs are modeled as causing failures.

unnecessary complexity in the memory.

TABLE I
AVERAGE NUMBER OF ERRORS PER EVENT

	65nmA	65nmB	45nmA	45nmB
α	2.0649	2.0649	1.9062	1.7573

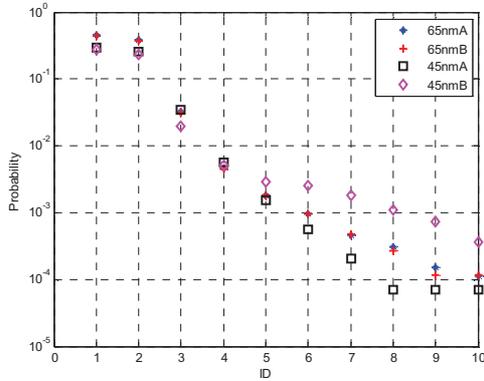


Fig. 2. Values of e^{ID} obtained in the experiments.

Therefore, the objective is to find the minimal ID that produces a reasonable MTTF in the memory.

With the previously described parameters, expressions (3) and (4) can be used to estimate the MTTF for direct and accumulation failures. Then using equation (6), the MTTF of the memory can be approximated. From the memory designer perspective, the main concern is choosing the minimal ID, but with a negligible impact of direct failures on the MTTF.

This negligible impact would imply that $e^{ID} \rightarrow 0$ (no direct failures due to MCUs). Therefore, according to (2), $MTTF_d \rightarrow \infty$, what would lead to $MTTF_{memory} \rightarrow MTTF_a$, per expression (6). In other words, the Mean Time to Failure of the memory would only be affected by the accumulation of several independent events. Therefore, the closer the ratio $MTTF_{ratio} = MTTF_{memory} / MTTF_a$ is to 1, the less impact of direct failures. As this ratio decreases from 1, that would represent a decrement of the MTTF due to those direct failures. For example, given a value of ID, a ratio of 0.8 would mean that the reliability of the memory is 80% of its optimal value due to the direct failures caused by large MCUs that cannot be handled by the interleaving. In this case, a higher ID would be advisable (what would lead to a higher MTTF ratio).

In this way, the effect of the interleaving distance is quantified, helping the designer with the selection of an optimal value.

Considering the case under study, the value of the ratio has been computed using expression (6) for the different geometries, implementing various IDs and memory sizes. The results are presented in Figures 3 to 6. Analyzing the plots the following observations can be made. First, as the memory size increases, larger ID values are needed to ensure a small impact of direct failures (high MTTF ratios). This can be explained as for larger memories, more errors are needed to cause a failure by error accumulation and therefore even a small percentage of errors causing direct failures will affect the reliability. The conclusion is that the optimal ID tends to grow with the memory size. The second observation is that the four memories follow a similar trend, and therefore similar IDs

would produce a similar impact on all of them.

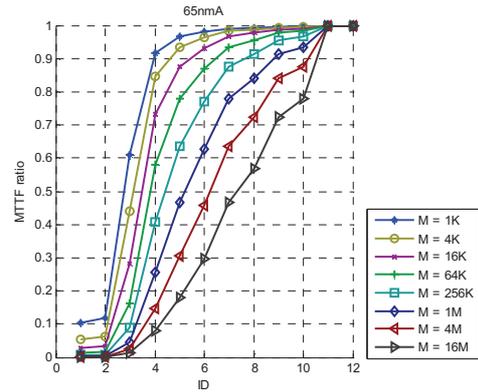


Fig. 3. $MTTF_{ratio}$ for the 65nmA memories in different configurations

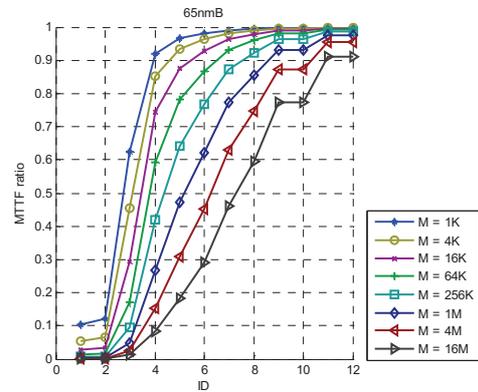


Fig. 4. $MTTF_{ratio}$ for the 65nmB memories in different configurations

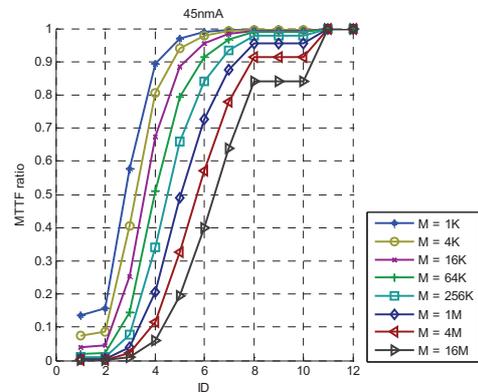


Fig. 5. $MTTF_{ratio}$ for the 45nmA memories in different configurations

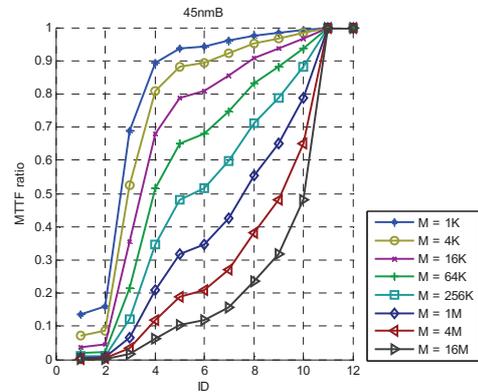


Fig. 6. $MTTF_{ratio}$ for the 45nmB memories in different configurations

In order to make a more detailed analysis of the ID vs reliability trade-off, let us now focus on the design of a 256-Kword memory. Let us also consider a reliability goal such that direct failures can only have an effect of 10% or less on the MTTF. Then, using the plots in figures 3 to 6, the minimal ID distances can be obtained in order to meet that goal. These results are depicted in Table II where a conservative value for the ID is also proposed. The conservative ID is defined in such a way that direct failures have a negligible impact, thus having no effect on the MTTF. The results show that ID values smaller than the maximum MCU size can be used in some cases. This will reduce the area and power of the memory making the design more competitive. To illustrate the benefits of the proposed approach, the cost of a memory with the previously selected ID values has been compared. The cost calculation is based on data from [11], summarized in Table III where the relative area/power overhead versus an ID of four are shown. The ID values available are only powers of two in this particular memory design, a situation that is common unless a full-custom design is made. It can be seen that both the area and power increase significantly with the ID.

In Table IV, the relative area overhead has been described for the ID values determined in Table II. For each case presented in Table II the closest power of two that is equal or larger than the required ID in each case (ID_{min} , $ID_{conservative}$) is selected from Table III. Those values are also shown in parenthesis in Table II. The results for the power consumption overhead are shown in Table V.

The results show that the area and power can be significantly reduced in this case for three of the memory types (65nmA, 65nmB, 45nmA) with a negligible impact on reliability, using ID_{min} as described before, versus the conservative ID values (which will be the natural choice if this methodology is not applied). Therefore the proposed ID selection process achieves the goal of choosing the ID that minimizes the cost without impacting reliability.

TABLE II
ID VALUES

	65nmA	65nmB	45nmA	45nmB
ID_{min}	8 → (8)	8 → (8)	7 → (8)	11 → (16)
$ID_{conservative}$	11 → (16)	12 → (16)	11 → (16)	11 → (16)

TABLE III
AREA OVERHEAD FOR DIFFERENT ID VALUES

ID	Area increment	Power Increment
4	1	1
8	1,027	1,072
16	1,316	1,247
32	2,031	2,016

TABLE IV
AREA INCREMENT FOR THE TWO ID CONFIGURATIONS

	65nmA	65nmB	45nmA	45nmB
ID_{min}	1,027	1,027	1,027	1,316
$ID_{conservative}$	1,316	1,316	1,316	1,316

TABLE V
POWER INCREMENT FOR THE TWO ID CONFIGURATIONS

	65nmA	65nmB	45nmA	45nmB
ID_{min}	1,072	1,072	1,072	1,247
$ID_{conservative}$	1,247	1,247	1,247	1,247

IV. CONCLUSIONS

In this paper, the reliability of memories that use SEC and interleaving has been analyzed. A procedure to ensure that failures caused by MCUs exceeding the ID have a negligible impact on reliability has been presented. The procedure helps memory designers choose the minimal ID (thus reducing area and complexity), but assuring an appropriate reliability level. A case study has also been presented showing the potential benefits of the proposed approach using real radiation data. The results show that significant area and power savings can be obtained in some cases.

Another interesting observation from the analysis is that larger memories are more likely to need larger ID values, as they tolerate less percentage of MCUs exceeding the ID. As technology shrinks, MCUs tend to affect more cells and memories tend to be larger. Those two factors will reinforce the need for larger ID in future memory designs. This in turn will result in a larger area and power overhead due to the ID.

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